

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT: COPPOLA, Giuseppe; FERRARO, Pietro; IODICE, Mario; DE NICOLA, Sergio

SERIAL NO.:

FILED: Herewith

TITLE: INTERFEROMETRIC SYSTEM FOR THE SIMULTANEOUS MEASUREMENT OF THE INDEX OF REFRACTION AND OF THE THICKNESS OF TRANSPARENT MATERIALS, AND RELATED PROCEDURE

PRELIMINARY AMENDMENT

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

Sir:

In conjunction with the filing of the present application, and prior to an initial Official Action on this matter, please amend the above-identified application as follows:

Preliminary Amendment: SPECIFICATION AMENDMENTS

In Paragraph [0009], please amend the paragraph as follows:

The invention is now being described on the basis of a version at present preferred by the inventors and with reference to the attached drawings: drawings.

In Paragraph [0010], please amend the paragraph as follows:

~~Fig. 1 - Schematic representation~~ Figure 1 is a schematic view of the system for the simultaneous measurement of the index of refraction and the thickness of transparent materials.

In Paragraph [0011], please amend the paragraph as follows:

~~Fig. 2 - Schematic representation~~ Figure 2 is a schematic view of the sample of material to be used with the relevant variations of direction of the incident radiation.

In Paragraph [0012], please amend the paragraph as follows:

~~Fig. 3 - Diagram~~ Figure 3 is a diagrammatic illustration showing graphically the interferometric signal obtained upon varying of the angle of incidence and for each wavelength of the coherent tuneable light source.